

EB 1 9 2002

V026159219

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/905,320
Filing Date July 13, 2001
Inventor Cem Basceri et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner Eric Fuller
Attorney's Docket No. MI22-1657
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate Comprising Dielectric Layers, Including Such Layers Having a Varied Concentration of Barium and Strontium Within the Layer

RESPONSE TO DECEMBER 19, 2001 OFFICE ACTION

To: Box Non-Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

VIA EXPRESS MAIL

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells, St. John, Roberts, Gregory & Matkin P.S.
601 West First Avenue, Suite 1300
Spokane, WA 99201-3828

Responsive to the Office Action dated December 19, 2001, Applicant amends and remarks as follows:

AMENDMENTS

In the Specification

Please replace the paragraph beginning at line 6 on page 19 with the following clean replacement paragraph in accordance with 37 CFR § 1.121(b)(1)(ii). A marked-up version showing amendments to the specification paragraph being changed is provided in one or more

MI221657.M01

PAT-US/AM-00

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